



Docket No.: 49657

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Customer Number: 20277
Kenji ITOGA, et al. : Confirmation Number: 5521
Application No.: 09/769,490 : Group Art Unit: 2882
Filed: January 26, 2001 : Examiner: Kao, Chih Cheng G.
For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK,
X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON
RADIATION METHOD AND SEMICONDUCTOR DEVICE

AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Notice of
Allowance and Notice of Allowability dated January 12, 2005.